

Replace the paragraph on page 1, lines 8-18, as follows:

a2
Of conventionally-known apparatuses for inspecting defects of LCD glass substrates, some apparatuses are known in which defects (e.g., scratches) formed in the surface of the glass substrate can be checked by using a macro observation and a micro observation interchangeably. In the macro observation, light is applied onto the surface of the glass substrate and then optical change of the reflected glass is observed, thereby detecting the defects. In the micro observation, the defects found by the macro observation are magnified and observed.

Replace the paragraph on page 1, line 19 through page 2, line 1, as follows:

a3
For example, Jpn. Pat. Appln. KOKAI No. 5-322783 employs the macro observation system and the micro observation system which are set so as to correspond to an X-Y stage designed movable horizontally in X and Y directions. In the apparatus, the macro observation or the micro observation is performed by mounting a substrate on the X-Y stage and bringing a portion of the substrate to be inspected (defect) into an observation field of the macro

a3
conced

observation system or the micro observation system by moving the X-Y stage two-dimensionally in the X and Y directions.

Replace the paragraph on page 2, lines 2-11, as follows:

a4

Recently, the size of the glass substrate has tended to be increased with an enlargement of LCDs. In the case where such a large glass substrate is inspected by using the inspecting apparatus having the X-Y stage which is movable horizontally and two-dimensionally (X, Y directions), an area four times as large as the area of the glass substrate is required as a space for moving the X-Y stage. Therefore, the substrate inspecting apparatus has inevitably become large with the increase in size of the glass substrate.

Replace the paragraph on page 2, lines 12-19, as follows:

a5

Furthermore, in the conventional inspection apparatus, it is difficult to inspect a small scratch since the surface of the substrate is far away from an eye position of the inspector. Moreover, it is difficult to obtain positional data of the defect found in the surface of the substrate. Accordingly, it is been impossible to inspect the substrate highly accurately.

Replace the paragraph on page 12, line 12 through page 13,
line 9, as follows:

a6

FIG. 6 shows how to inspect a substrate by use of the inspecting apparatus of the present invention. As shown in FIG. 6, an entire-area illuminating macro light source 30 is set above the main apparatus 1. The macro light source irradiates the entire area of the surface of the substrate 3 on the holder 2. The macro light source 30 comprises a metal halide lamp 31 serving as a point light source, a reflecting mirror 32 arranged so as to face the metal halide lamp 31, and a fresnel lens 33 arranged below the reflecting mirror 32. The reflecting mirror 32 is tilted at an angle of 45° with the main apparatus 1 and plays a role in reflecting light incident from the metal halide lamp 31 and injected into the fresnel lens 33. The fresnel lens 33 converges the light reflected by the reflecting mirror 32, as shown in the figure, and injects the converged light over the entire surface of the substrate 3 on the holder 2. Note that, as shown in FIG. 1, the main apparatus 1 has a Y-scale 13 for detecting the position coordinate of the observation unit supporting section 5 in the Y-axis direction. An X-scale 14 is provided on the observation unit supporting section 5 for detecting the position coordinate of the observation unit 6 in the X-axis direction.